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Minimization of Surface Impurities in Anodized Aluminum

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I. Introduction

Anodized aluminum is commonly used to create wear-resistant parts for process tools used in the semiconductor industry. Since microchips require high purity manufacturing environments [1], surface impurities on tooling needs to be minimized.

It has been determined that anodized aluminum parts are one source of contamination. This project investigates the source of trace elements in anodized aluminum 6061 parts and ways to reduce them.

II. Background

NxEdge, the project sponsor, uses aluminum 6061 T6 alloy for their wafer manufacturing components. The composition of this alloy (in wt%) is as follows [2]:

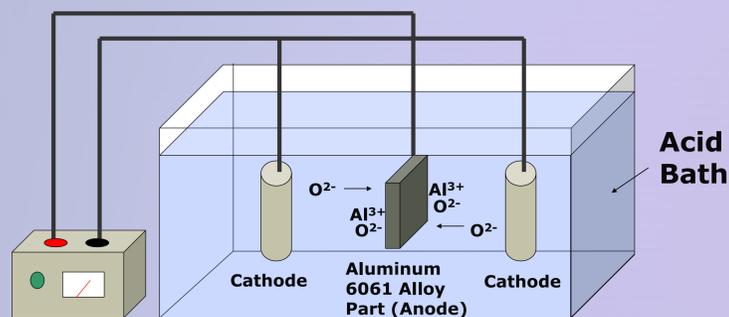
Si	Fe	Cu	Mn	Mg	Cr	Ni	Zn	Ti	V
0.650	0.350	0.30	0.05	1.00	0.023	0.05	0.08	0.04	0.01

Many of these elements are considered contaminants in the semiconductor industry.

Anodizing

NxEdge uses Type III hard anodizing on many products.

- Negative charge carried by oxygen from cathode to part
- O^{2-} combines with Al^{3+} to neutralize and form Al_2O_3
- Type III – oxide is grown relatively thick (25-50 μm)
- Hot water bath to seal porous alumina surface



Pros of Anodizing:

- Robust and corrosion resistant surface
- Resistant to abrasion
- Thermally and electrically insulative

Cons:

- Impurities from acid bath
- Alloy elements act as impurities and cause discontinuities in oxide

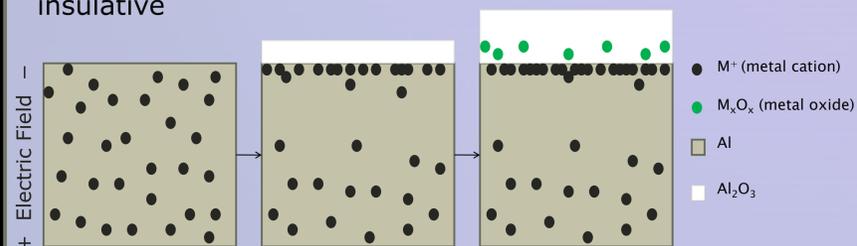
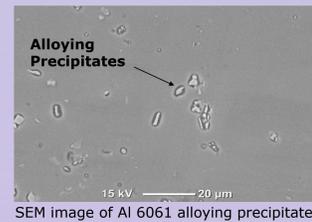
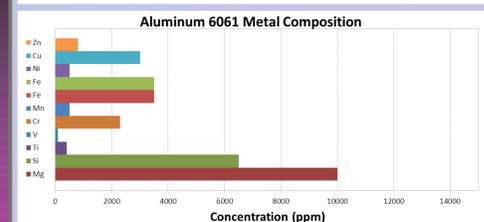
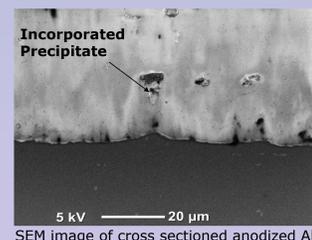
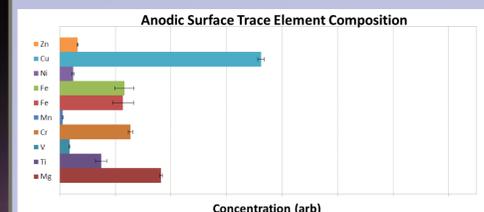


Diagram showing the migration of highly mobile metal cations collecting at the interface before incorporating with the oxide during anodizing.

III. Approach

Preliminary Characterization

Scanning Electron Microscopy (SEM)
Laser Ablation Inductively Coupled Plasma Mass Spectrometry (LA-ICP-MS)



- Negligible variation in trace element concentration between 6061 samples at various steps in anodizing process, strong correlation between substrate and oxide

Methods – Three methods to reduce trace elements were developed based on preliminary characterization.

Method 1:

Reduced current density

- Impurities migrate to anodic oxide layer by drift
- Lower current density should lower the drift velocity

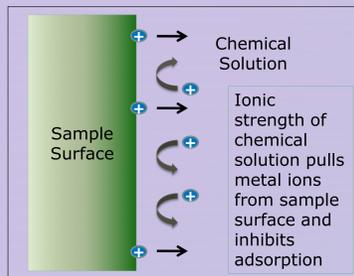
$$v_d = \frac{I}{nqA}$$

v_d = drift velocity
 I = current
 n = # of ions
 q = charge of ions
 A = area of cross section

Equation representing drift velocity for Method 1

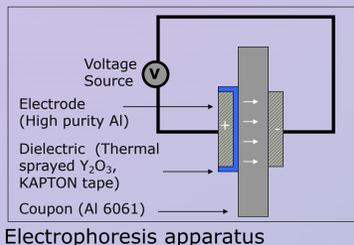
Method 2: Modified Rinse

- Designed to clean semiconductors
- Ultrasonic bath with chemical solution following anodizing and boil seal steps (Process 1) or just boil seal (Process 2)



Method 3: Electrophoresis

- Evidence of ion migration during anodizing
- High electric potentials drive metal cations further into substrate and reduce surface impurities



Acknowledgments

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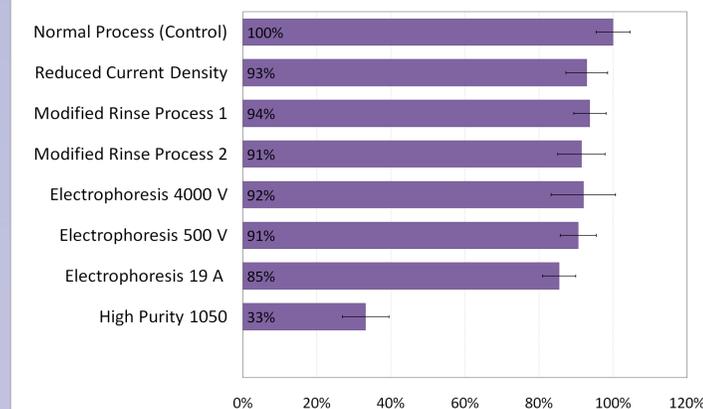
V. Results

- Trace elements concentrations to determine method effectiveness

- Concentrations determined using a Newave Research LA-ICP-MS system.

- Minor decreases in total trace elements for all methods

Total Concentrations Normalized to Control



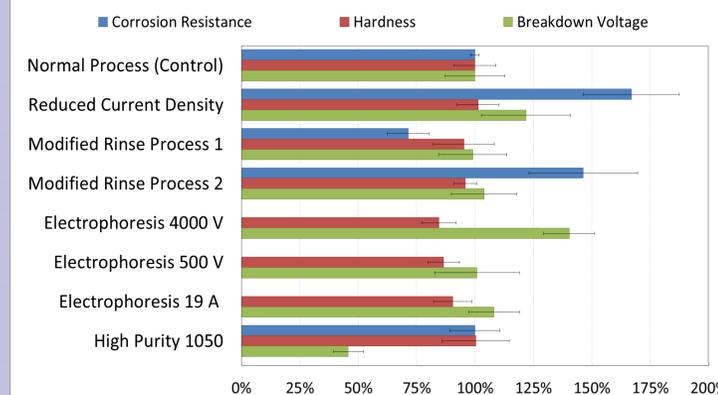
- Corrosion resistance, hardness, and breakdown voltage tested to measure performance

- Reduced Current Density had best results

- High purity Al 1050 series was tested to look for any changes in performance

- Low breakdown for Al 1050 series

Performance Results Normalized to Control



VI. Conclusions

- Starting material is the main source of contaminant elements in the anodic oxide layer
- Using a high purity substrate or surface is the most effective method for reducing contaminants
- Prototypes created with Reduced Current Density or Modified Rinse Process 2 remained robust, crucial for reducing rate of contamination
- Using high purity aluminum substrate or coatings may drastically lower impurities while maintaining good hardness and corrosion resistance

VII. Future Work

- Experimentation with various current densities or lower voltages
- Studies on bath life, dilution, and optimization of modified rinse process
- Optimization of parameters for electrophoresis to achieve its full capabilities
- Investigate use of coating with high purity aluminum prior to anodizing

References

1. R. McFadden. A Basic Introduction to Clean Rooms. Available at: <http://www.coastwidelabs.com/Technical%20Articles/Cleaning%20the%20Cleanroom.htm>
2. "Alcoa Spectrochemical Standards," A. I. S. M. Division, Ed., ed. Pittsburgh, PA, 2004, p. 18.